

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings of claims in the application:

LISTING OF CLAIMS:

1.(currently amended) ~~Method~~ A method of depositing an amorphous layer containing ~~mostly~~ fluorine and carbon on a substrate in a vacuum, ~~characterized in that it includes a step of~~ comprising:

depositing said amorphous layer ~~by means of~~ via an ion gun adapted to eject ions in ~~[[the]]~~ a form of a beam of accelerated ions created from at least one compound containing fluorine and carbon in gas or saturated vapor form fed to the ion gun,

wherein the amorphous layer containing fluorine and carbon is an exterior layer of an antireflection stack of an ophthalmic lens deposited on the substrate,

said exterior layer having a refractive index characteristic for fluorocarbons.

2.(canceled)

3.(currently amended) ~~Method~~ The method according to claim 1, ~~characterized in that~~ wherein the ion gun is fed with

the at least one compound containing fluorine and carbon mixed with oxygen or at least one rare gas.

4.(currently amended) ~~Method~~ The method according to claim 1, ~~characterized in that~~ wherein the ion gun is fed with the at least one compound which comprises at least one aliphatic or cyclic fluorocarbon compound, at least one aliphatic or cyclic fluorinated hydrocarbon, or a mixture thereof.

5.(currently amended) ~~Method~~ The method according to claim 4, ~~characterized in that~~ wherein the ion gun is fed with perfluorocyclobutane (C_4F_8) or a mixture ~~thereof~~ with at least one other fluorocarbon compound comprising ~~in particular~~ tetrafluoromethane (CF_4) or hexafluoromethane (C_2F_6), or at least one rare gas.

6.(currently amended) The method according to claim 1, ~~characterized in that~~ wherein the substrate is a plastics material substrate.

7.(currently amended) The method according to claim 1 [[2]], ~~characterized in that it consists in~~ further comprising fabricating ~~an~~ the antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from ~~the~~ an interior toward the exterior, a layer having a first high refractive index/a layer having a second low refractive index/a layer having the first high refractive index, preferably of the type or a stack of $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$; and

- depositing the ~~amorphous external layer~~ exterior layer containing mostly fluorine and carbon using the ion gun, wherein the second refractive index is lower than the first refractive index.

8.(currently amended) The method according to claim 7, ~~characterized in that~~ wherein ~~each in vacuo the~~ PVD step includes evaporation by electron bombardment of the material to be deposited.

9.(currently amended) The method according to claim 7, ~~characterized in that~~ wherein each deposition step is carried out at a pressure less than or equal to 10^{-2} Pa.

10.-16. (cancelled)

17.(currently amended) ~~Method~~ The method according to claim 1 ~~[[2]]~~, ~~characterized in that~~ wherein the ion gun is

fed with the at least one compound containing fluorine and carbon mixed with oxygen or at least one rare gas.

18.(currently amended) ~~Method~~ The method according to claim 8, ~~characterized in that~~ wherein each deposition step is carried out at a pressure less than or equal to 10^{-2} Pa.

19.(currently amended) ~~Method~~ The method according to claim 17, ~~characterized in that it consists in~~ further comprising fabricating an antireflection stack by the following steps:

- physical vapor-phase deposition (PVD) in a vacuum of three layers respectively having, from the interior toward the exterior, a high refractive index/a low refractive index/a high refractive index, ~~preferably of the type~~ or $\text{ZrO}_2/\text{SiO}_2/\text{ZrO}_2$;

- depositing the amorphous external layer containing mostly fluorine and carbon using the ion gun.

20.(cancelled)

21. (new) The method according to claim 1, wherein the refractive index characteristic of fluorocarbons is 1.35-1.39.